Gas supply system for high- and low-pressure gas-consuming apparatuses and method of controlling such a system

Abstract

The present invention relates to a system (1) for supplying gas to a high-pressure gas-consuming apparatus (4) and a low-pressure gas-consuming apparatus (5) of a floating structure comprising a tank (8), the supply system (1) comprising:

- a first supply circuit (2),
- a second supply circuit (3),
- a return line (14),
- a first heat exchanger (6) and a second heat exchanger (7), the return line (14) comprising a flow-regulating member (15),

characterized in that the supply system (1) comprises a device (80) for managing said supply system (1) which comprises a control module (86) configured to control the flow-regulating member (15) based on the characteristics of the gas.

Fig. 1